Docket No.: 005191C1(Y2)/ISM/CORE/MCVD/PJS

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Lawrence C. Lei

Serial No.: 10/792,323

Confirmation No.: 4370

Filed: March 3, 2004

For: APPARATUS AND METHOD FOR VAPORIZING SOLID PRECURSOR FOR CVD OR ATOMIC

LAYER DEPOSITION

Group Art Unit: 3742

Examiner:

Sang Y. Paik

## AMENDMENT IN RESPONSE TO NON-FINAL OFFICE ACTION

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MS Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

## INTRODUCTORY COMMENTS

In response to the Office Action dated August 24, 2007, please amend the above-identified U.S. patent application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 5 of this paper.